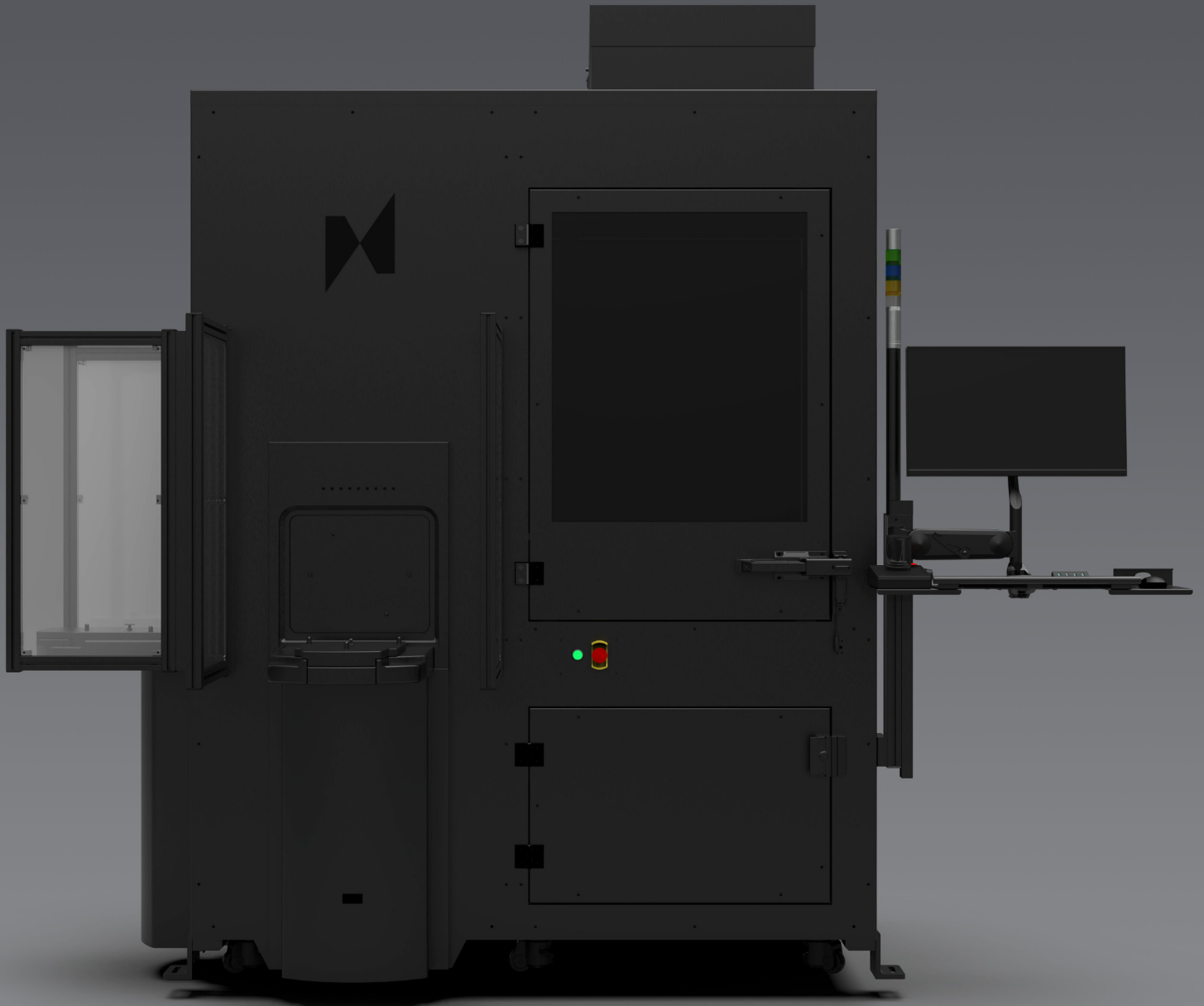


nSpec[®] CPS

300mm Automated Optical Inspection System



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nSpec[®] CPS

300mm Automated Optical Inspection System

Whatever the user's specific sample inspection requirements, Nanotronics provides a wide range of solutions for obtaining rapid results.

nSpec[®] CPS is the ideal system for highly controlled clean room environments.

This system runs multiple scans sequentially. User-friendly software makes configuring recipes next to effortless. And, as needs evolve, recipes are easy to save and modify.

This 300 mm design supports:

- HEPA air filtration
- Air ionizers
- Automatic load ports

Features:

- Automatic wafer handling
- Multiple resolution settings, ranging from 0.25 μm and greater
- Rapid scanning
- Customizable defect reports
- Settings for single image capture and scans
- Variety of sample chucks to meet specific needs
- Robust analysis for defect or feature of interest detection and classification
- Inspection and review procedures
- Multi-system synchronization
- Small footprint and minimal facilities requirements
- Rack mount controls
- Door interlocks

SYSTEM

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Weight	540 kg
Dimensions (W x D x H)	158 cm x 173 cm x 202 cm
Min. Vacuum Requirement	-21 in. Hg (-70 kPa)
Power Supply	120VAC, 30A, 50-60Hz 208VAC, 15A, 50-60Hz

OPTICS

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Illumination Modes	Brightfield, Darkfield, DIC (Nomarski)
Light Source	White light LED (other options available)
Objectives	2.5, 5, 10, 20, or 50x, user selectable

STAGE

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Travel, typical	350 mm X and Y direction
Positioning	Linear servo motors with closed loop encoders (50 nm resolution)
Repeatability	+/- 0.5 μm
Travel Flatness	20 μm
Construction	Precision ground raceways and high rigidity linear guideways
Mounting Platform	Isolated platform integrated into cabinet system
Centered Load Capacity	5 kg

OPTIONS

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AFM	Specs available upon request
SECS/GEM	
OCR	
Air Ionizers^o	

